

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Rosengaus et al.

Attorney Docket No.: KLA1P001C1

Application No.: 09/474,941

Examiner: Rosenberger, R.

Filed: December 30, 1999

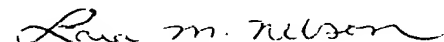
Group: 2877

Title: SYSTEM AND METHOD FOR  
INSPECTING SEMICONDUCTOR WAFERS

## CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail to: Commissioner for Patents, Washington, DC 20231 on December 6, 2001.

Signed:



Lara M. Nelson

AMENDMENT TRANSMITTAL

Commissioner for Patents  
Washington, DC 20231

Sir:

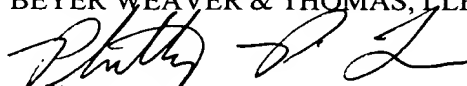
Transmitted herewith is an Amendment in the above-identified application.

The fee has been calculated as shown below.

	Claims After Amendment		Highest Previously Paid For	Present Extra	Small Entity Rate Fee	Large Entity Rate Fee
Total Claims	30	MINUS	32	00	x 9 =	x 18 =
Independent Claims	07	MINUS	07	00	x 42 =	x 84 =
Multiple Dependent Claim Present and Fee Not Previously Paid					\$140.00	\$280.00
Total					\$	\$

- ☐ Applicant(s) hereby petition for a \_\_\_\_\_ month extension(s) of time to respond to the aforementioned Office Action.
- ☒ Applicant(s) believe that no (additional) Extension of Time is required; however, if it is determined that such an extension is required, Applicant(s) hereby petition that such an extension be granted and authorize the Commissioner to charge the required fees for an Extension of Time under 37 CFR 1.136 to Deposit Account No. 500388.
- ☐ Enclosed is our Check No. \_\_\_\_\_ in the amount of \$\_\_\_\_\_ to cover the additional claim fee and/or extension of time fees.
- ☒ Please charge the required fees, or any additional fees required to facilitate filing the enclosed response, to Deposit Account No. 500388 (Order No. KLA1P001C1).

Respectfully submitted,  
BEYER WEAVER & THOMAS, LLP

  
Phillip P. Lee  
Reg. No. 46,866

P.O. Box 778  
Berkeley, CA 94704-0778

RECEIVED  
FEB - 5 2002  
TECHNOLOGY CENTER 2800

JAN 17 2002  
PATENT OFFICE

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Rosengaus et al.

Attorney Docket No.: KLA1P001C1

Application No.: 09/474,941

Examiner: Rosenberger, R.

Filed: December 30, 1999

Group: 2877

Title: SYSTEM AND METHOD FOR  
INSPECTING SEMICONDUCTOR  
WAFERS

14/E  
C. S. Stony  
2-8-02

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail to: Assistant Commissioner for Patents, Washington, DC 20231 on December 6, 2001.

Printed Name: Lara M. Nelson

Signed: Lara M. Nelson

RECEIVED  
FEB -5 2002  
TECHNOLOGY CENTER 2000

AMENDMENT D

Assistant Commissioner for Patents  
Washington, D.C. 20231

Dear Sir:

The Examiner is respectfully requested to enter the following amendments and consider the following remarks.

IN THE CLAIMS:

Please CANCEL claims 4, 11 without prejudice or disclaimer.

Please AMEND claims 1, 6, 9, 17, 43, 53, and 56 as follows:

1. (Five Times Amended) An integrated circuit manufacturing system comprising:
- (a) a plurality of interrelated integrated circuit manufacturing tools capable of operating in parallel on a plurality of semiconductor wafers, wherein the plurality of interrelated integrated circuit manufacturing tools comprise a cluster tool;
  - (b) a modular optical inspection system disposed proximate to a window of a central wafer handling chamber that is connected to each of the interrelated integrated circuit